

Surface Analysis of Organic Monolayers using FTIR and XPS

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- Introduction to Self-Assembled Monolayers (SAMs)
- Introduction to Surface Analysis (FTIR/XPS)
- Applications of SAMs
- Method #1: Solution Immersion
- Method #2: Molecular Self-Assembly
- Method #3: Electrochemical Reduction
- Summary of Findings
- Future Outlook
- Questions

Self-Assembled Monolayers

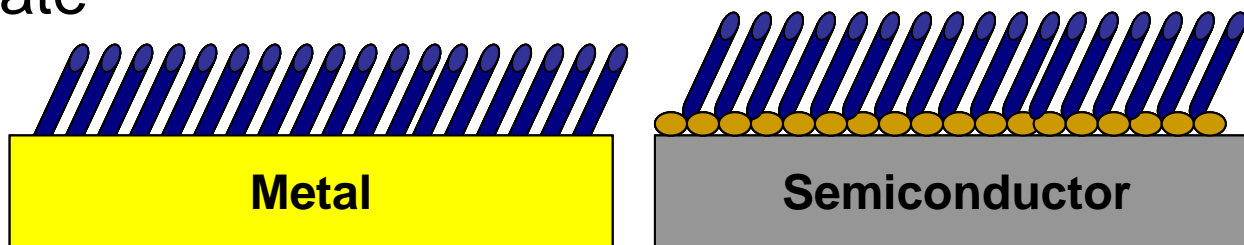
- Single layer of molecules
- Form spontaneously
- Well-defined structure
- Covalently bonded
- Bound to metal (Au, Ag, Cu) or semiconductor (GaAs, Si) substrate

GaAs (100) Substrate

- Alkanethiol molecules (-SH)
- Form S-As covalent bond

Si (111) Substrate

- Benzene molecules (-C₆H₁₂)
- Form Si-C covalent bond



Graphics Source: Patrick Carpenter

Preparation Techniques

• Molten Deposition

- Melt alkanethiols to 100-200 °C
- Deposit onto GaAs substrate
- Relatively effective
- Not usable on all alkanethiols

• Solution Immersion

- Etch substrate with HCL
- Rinse with DI H₂O
- Deposit substrate into solution
- Dry on hotplate (~8 hours)

• Activated NH₄OH Immersion

- Similar to solution immersion
- Etch with NH₄OH
- Allow to purge for 20 hours at room temperature

• Electrochemical Reduction

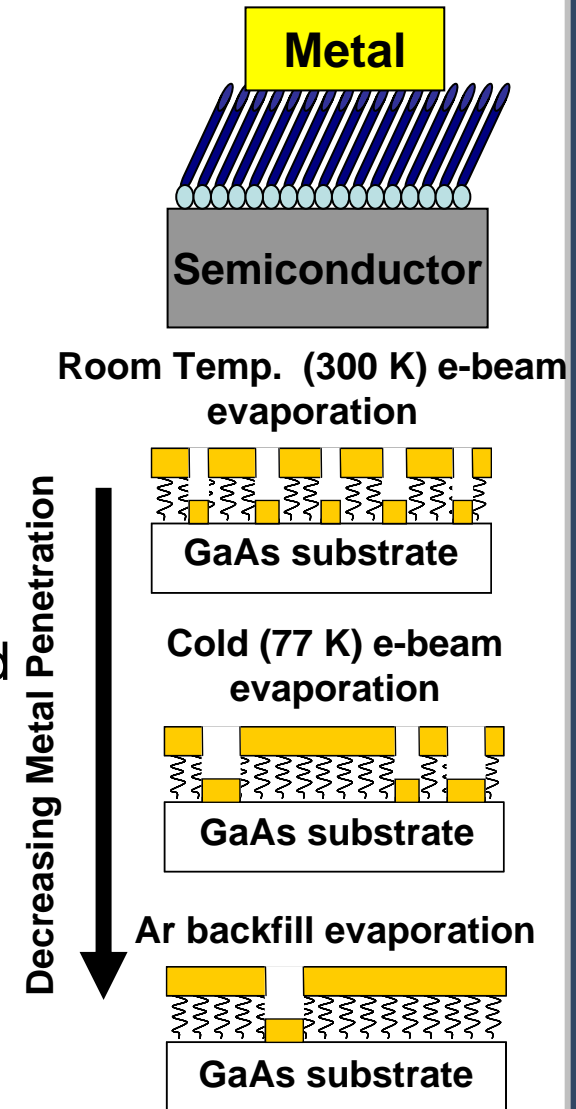
- Reduce aryl diazonium salts (C₆N₂BF₄) on Si
- Causes a radical reaction
- Useful for benzene monolayers

Purpose: Creation on nanoscale transistors

Problems: Metal penetration

Contacting Techniques

- Basic Principles:
 - Face substrate away from metal
 - Heat metal until reaches gaseous phase
 - Hot metal reaches substrate and is deposited
- Standard (300K): Pressure in chamber pumped down to 10^{-7} Torr and then sample deposited
- Cold (77K): Sample cooled with liquid nitrogen and slowly deposited
- Ar Backfill: Backfilled with Ar gas to slow KE



Graphics Source: Patrick Carpenter

- Scanning Electron Microscopy (SEM)

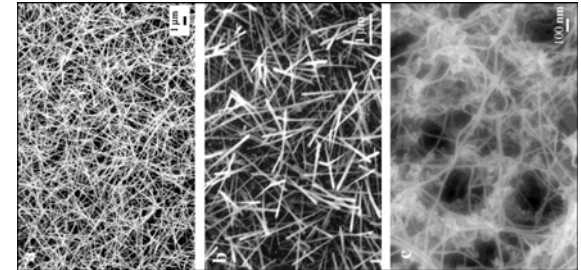
- Topography
- Morphology
- Composition
- Atomic arrangement

- Auger Electron Spectroscopy (AES)

- Elemental composition and concentration
- Mapping of elements
- Depth-profiling

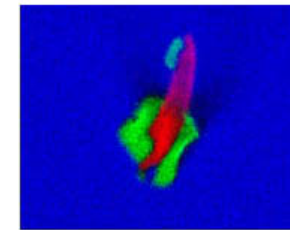
- Ellipsometry

- Layer thickness
- Composition
- Topography
- Optical constants

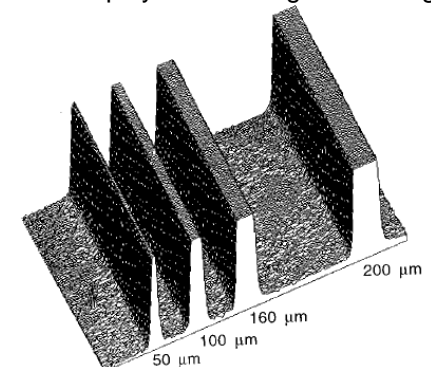


<http://www3.interscience.wiley.com/cgi-bin/fulltext/76509302/PDFSTART>

Color Composite Auger Map

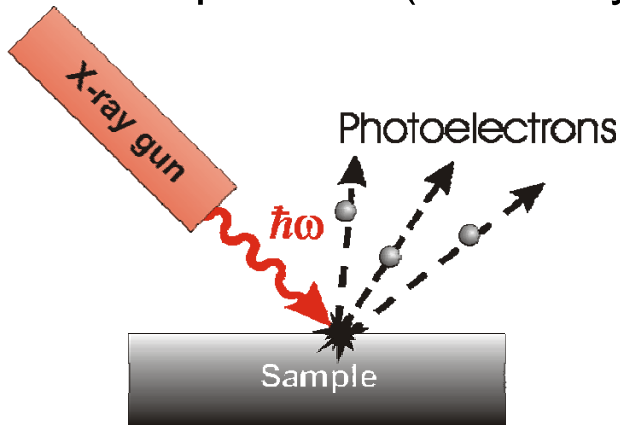


www.mate.calpoly.edu/.../images/aesimage.jpg

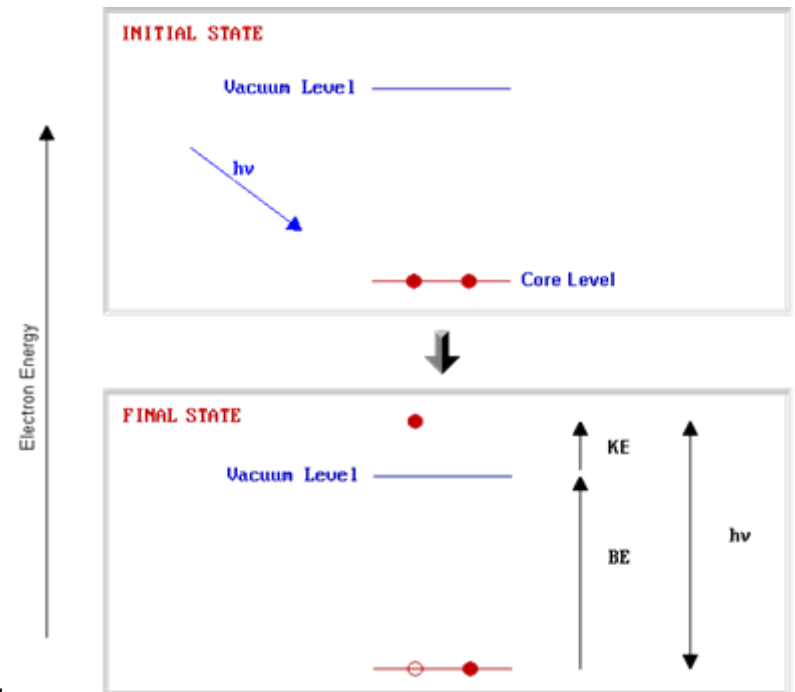


<http://scitation.aip.org/getpdf/servlet/GetPDFServlet?filetype=pdf&id=RSINAK00006700000800293000001&idtype=cvips&prog=normal>

- Uses photons (soft x-rays 200-2000 eV) to remove core electrons from sample = Photoemission

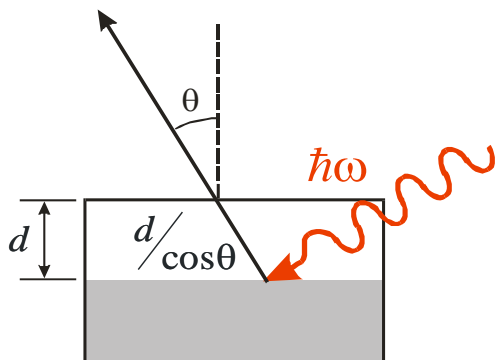


- Produces photoelectron spectrum by measuring the kinetic energy distribution of emitted photoelectrons
- Differences between the ionized electron and neutral electron = Binding energy (BE) which is direct measure of energy required to remove concerned electron
- Determines elemental concentration and electronic state of sample surface

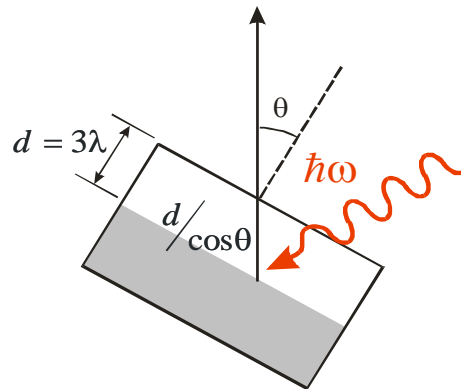


Images by Dmitry Zemlyanov (Purdue University)

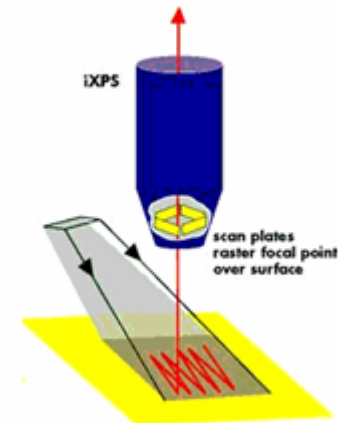
- Binding energy is dependent on:
 - Level at which photoemission is occurring
 - Formal oxidation state of the atom
 - Local and chemical environment
- * A change in the oxidation state or the environment will result in a chemical shift
- Other XPS capabilities



Depth-profiling



Angle Resolved XPS



X-Y Mapping

Images by Dmitry Zemlyanov (Purdue University)

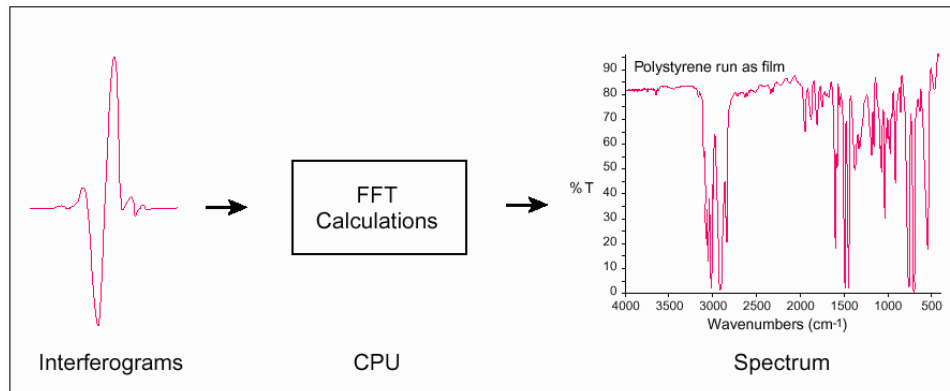
Basic Principle

- Fire IR-rays at sample
- Atoms (Bonds) within sample vibrate with specified frequencies

Uses of FTIR

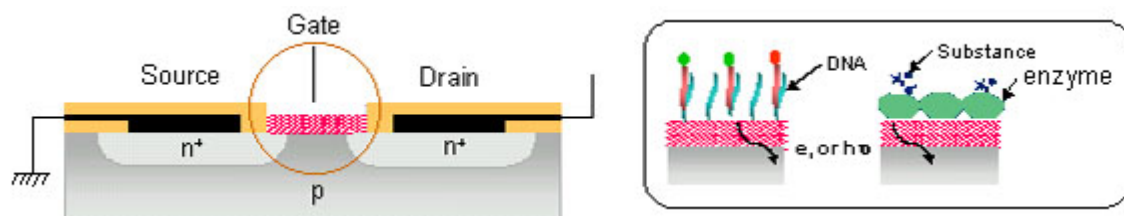
- Chemical Analysis
 - Match to known spectra
 - Match chemical groups
- Electronic Information
 - Measure optical conductivity
 - Determine whether metal, insulator, superconductor, semiconductor

$$W(x) \equiv \frac{2I(x) - I(0)}{\sqrt{2\pi}} = \frac{1}{\sqrt{2\pi}} \int_{-\infty}^{\infty} G(k)e^{ikx} dk$$



Images by http://spectroscopy.lbl.gov/FTIR-Martin/FTIR-Martin_files/frame.htm

- **Biological Sensors**

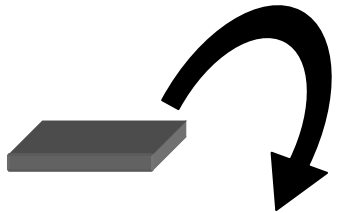


<http://www.coe.waseda.ac.jp/osaka/B-e.html>

- Biosensing system based on molecular recognition
- **Electrochemistry**
 - Sensors use monolayers to impart selectivity onto an electrode
 - Monitors pH, inorganic species, and organic molecules
- **Molecular Electronics**
 - Nanoscale insulators and dielectrics
 - Molecular switches
 - Rectifiers
 - Field effect transistors

- Use XPS and FTIR to characterize the surface of samples fabricated using three different techniques
- Analyze the results to determine elemental composition, percent oxidation, and atomic bonding
- Determine the effectiveness of each fabrication technique

Native oxide etch
with HCL



Addition of
 NH_4OH ,
deposit
sample, dry
on hotplate



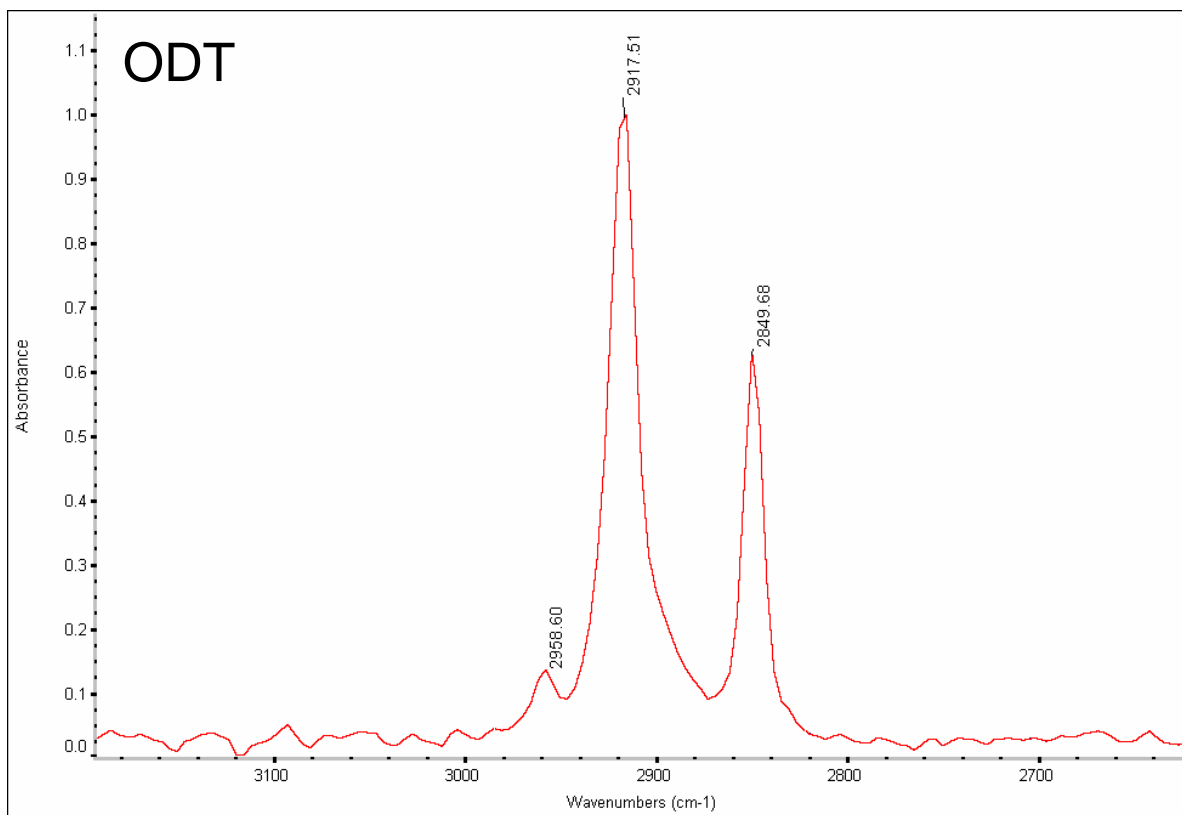
Substrate: GaAs (100)

Organic Molecule: 1-Octadecanethiol (ODT)

Covalent Bond: S-As

Procedure:

- 1) Oxide etched from GaAs using 1:9 HCL:DI solution
- 2) 5 mM molecule prepared, 5% (by volume) of 30% NH_4OH was added for continuing etching
- 3) Substrate then submerged into solution
- 4) Samples then purged with N_2 gas for 1 minute
- 5) Samples dried on 50° hotplate for 8 hours
- 6) Samples rinsed with ethanol after drying
- 7) Sample re-dried with N_2 gas



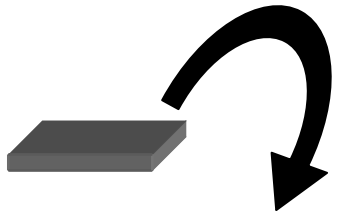
Peaks Present

- CH₂ peak (2917.51 cm⁻¹)
- CH₂ peak (2849.68 cm⁻¹)
- CH₃ peak (2958.60 cm⁻¹)

Indicates

- Fairly well ordered monolayer as shown by semi-sharp peaks and lower wavenumbers

Native oxide etch
with NH_4OH



Addition of
 NH_4OH ,
deposit
sample, dry
at room
temperature



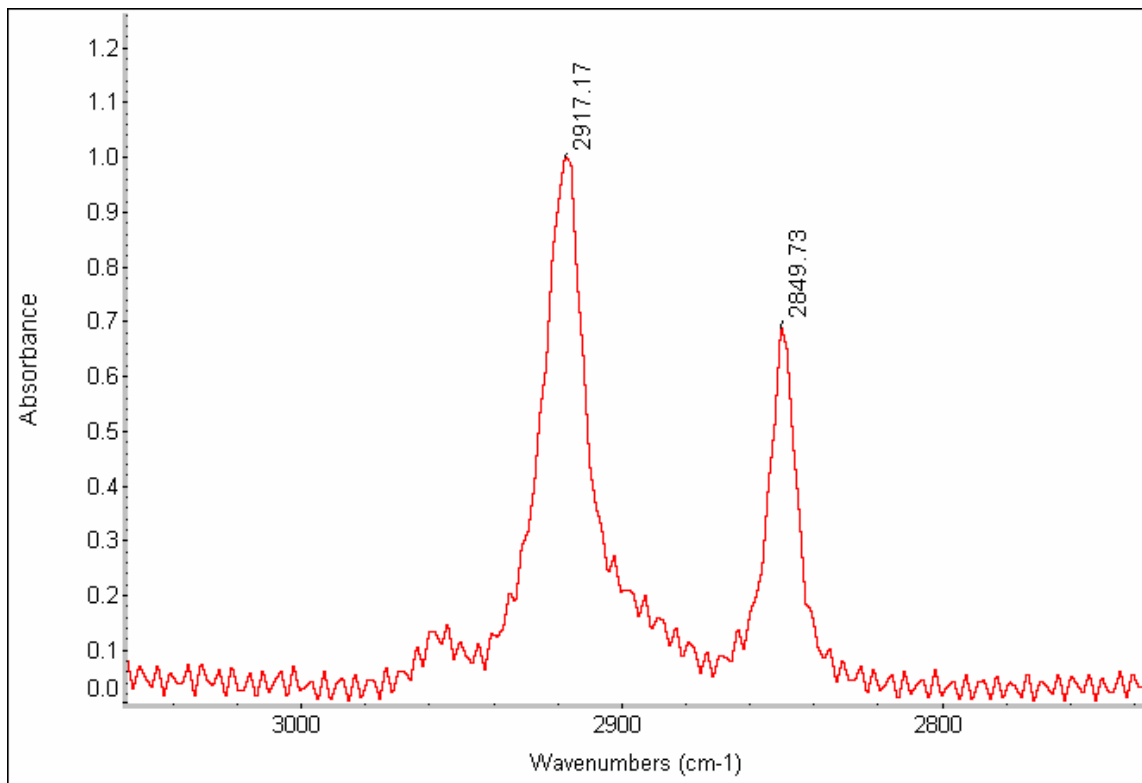
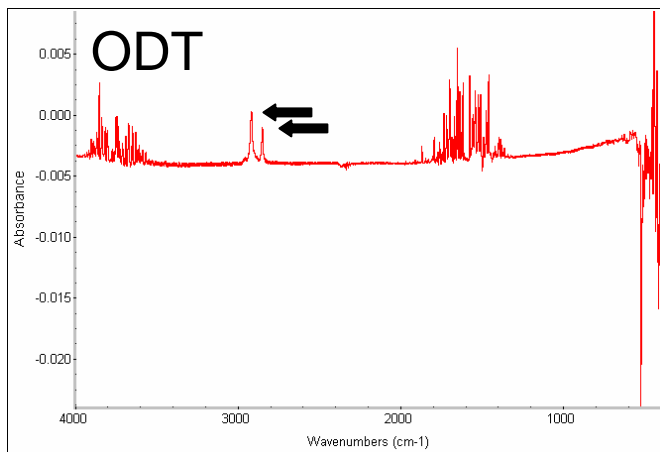
Substrate: GaAs (100)

Organic Molecule: 1-Octadecanethiol (ODT) and XYL

Covalent Bond: S-As

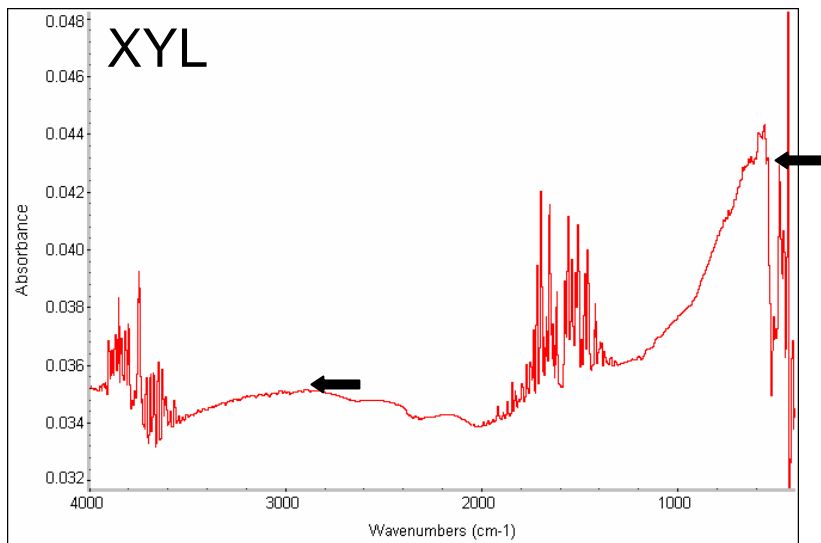
Procedure:

- 1) Oxide etched from GaAs using NH_4OH
- 2) 5 mM molecule prepared, 5% (by volume) of 30% NH_4OH was added for continuing etching
- 3) Substrate then submerged into solution
- 4) Samples then purged with N_2 gas for 1 minute
- 5) Samples dried at room temperature for 20 hours
- 6) Samples rinsed with ethanol after drying
- 7) Sample re-dried with N_2 gas

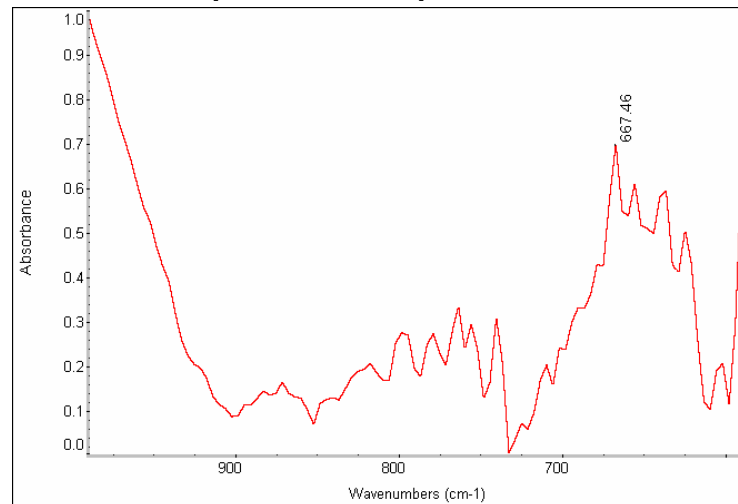


Octadecanethiol

- Expected: C-H₃ Stretch ~2850-3000cm⁻¹
C-H₂ Stretch ~1465cm⁻¹
- Peak present at 2917.17cm⁻¹, 2849.73cm⁻¹
- Peaks indicates successful monolayer formation
- Sharp peaks indicate highly ordered monolayer

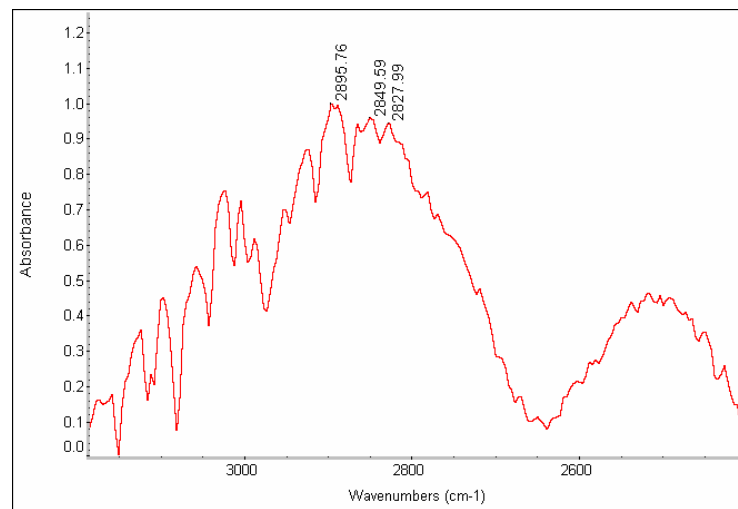


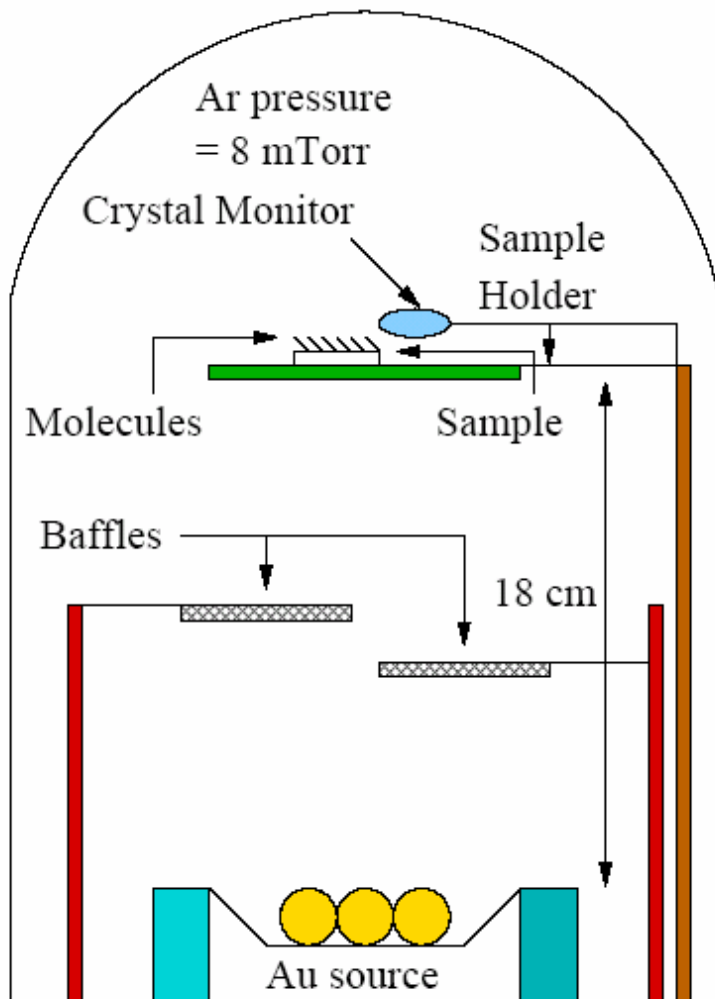
Expanded Spectrum



XYL

- Expected: C-H₃ Stretch ~2850-3000cm⁻¹
C-H₂ Stretch ~1465cm⁻¹
- Peak present at 2895.26cm⁻¹, 2849.59cm⁻¹
- Peaks indicates successful monolayer formation
- Semi-Sharp peaks indicate semi-ordered monolayer

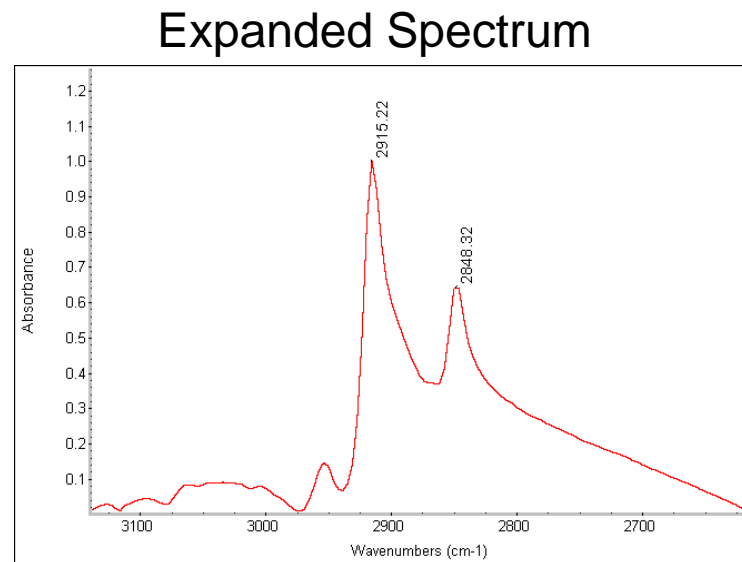
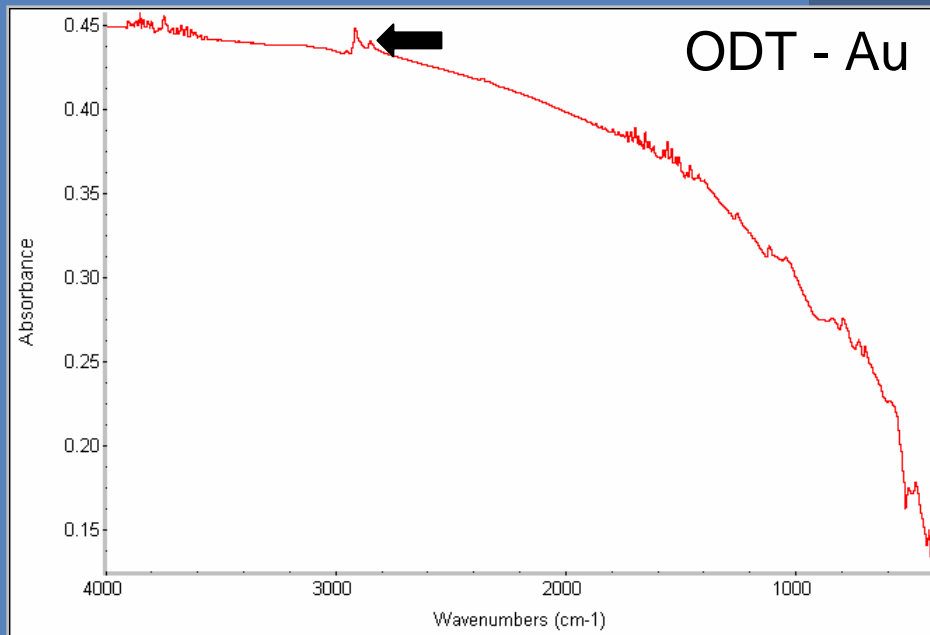




Graphics Source: Patrick Carpenter

Indirect Evaporation Procedure

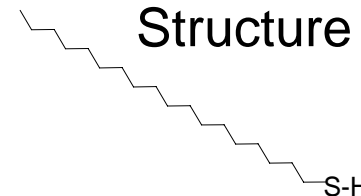
- 1) Substrate is faced away from metallic source and cooled
- 2) Argon is backfilled into the chamber during deposition
- 3) Metallic Au is heated
- 4) Argon slows the kinetic energy of evaporated Au particles
- 5) Reduced kinetic energy results in a lower quantity of penetration
- 6) A thin layer of Au is evaporated on the ODT organic monolayer



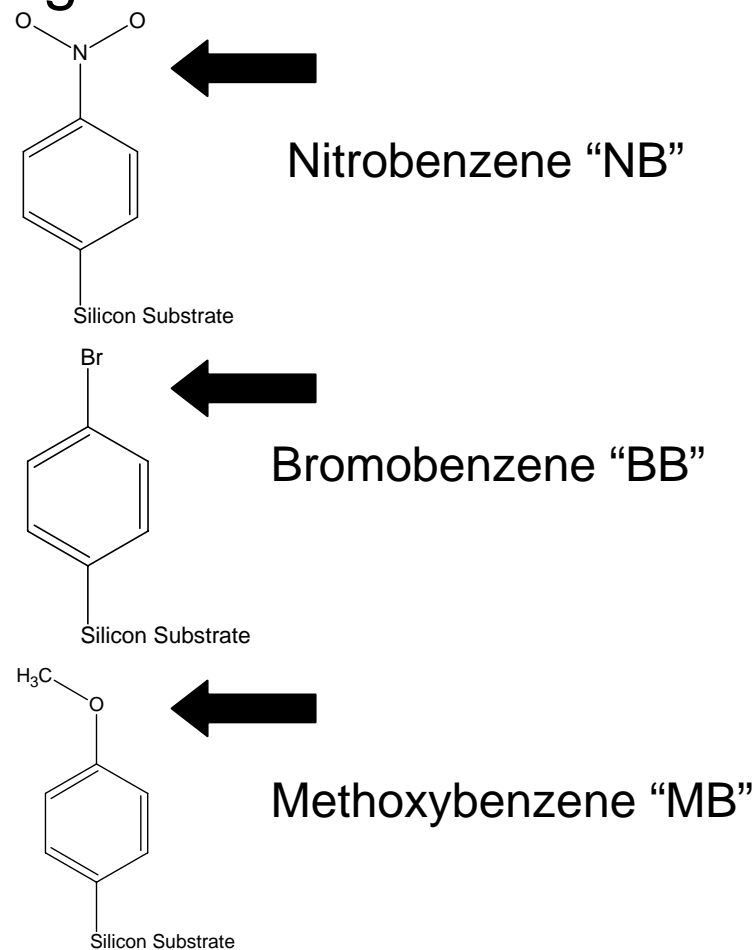
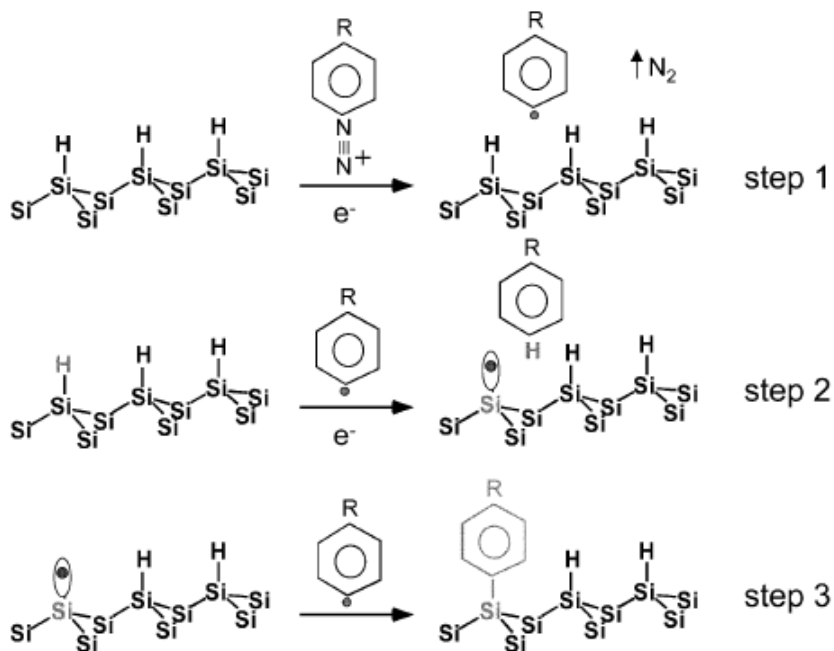
Octadecanethiol contacted with Au

- Expected: C-H₃ Stretch ~2850-3000cm⁻¹
C-H₂ Stretch ~1465cm⁻¹
- Peak present at 2915.22cm⁻¹, 2848.32cm⁻¹
- Correlates to peaks at 2917.17cm⁻¹, 2849.73cm⁻¹
- Indicates successful monolayer formation
- Indicates successful contact with Au

Molecular Structure

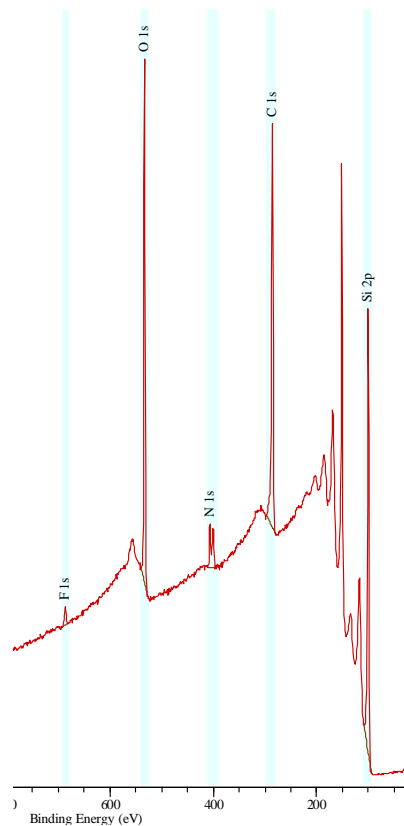


- Electrochemical reduction of aryl diazonium salts ($C_6N_2BF_4$) on Si(111) by promoting a radical reaction



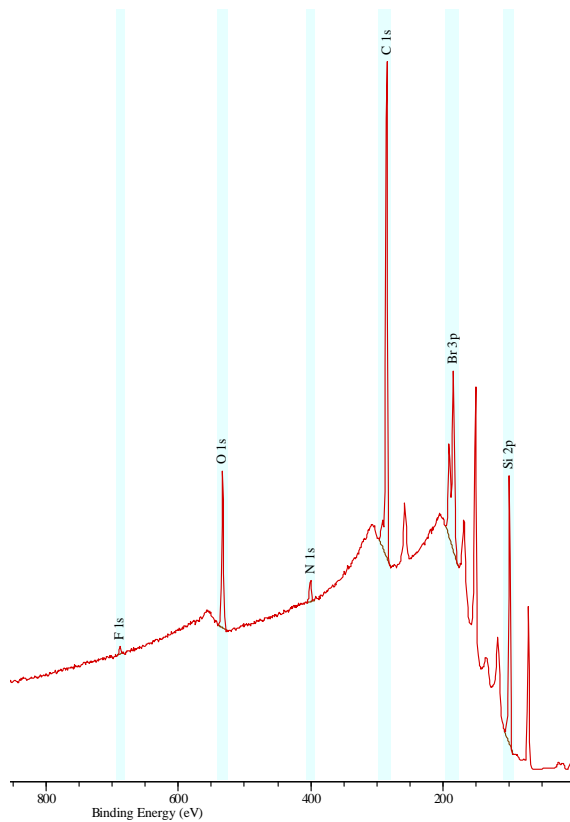
P. Allongue et al. / Journal of Electroanalytical
Chemistry 550/551 (2003) 161/174

NB Wide



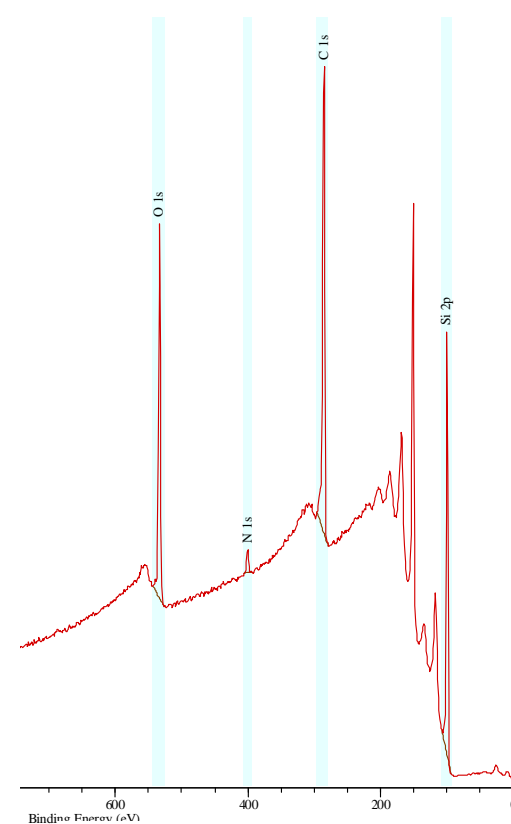
Name	Pos.	FWHM	Area	At%
O 1s	533	2.91125	23154.0	15.76
C 1s	286	3.13313	20026.4	39.95
N 1s	406	3.06303	4163.0	4.61
F 1s	687	3.154	909.7	0.41
Si 2p	100	2.54496	16079.8	39.26

BB Wide



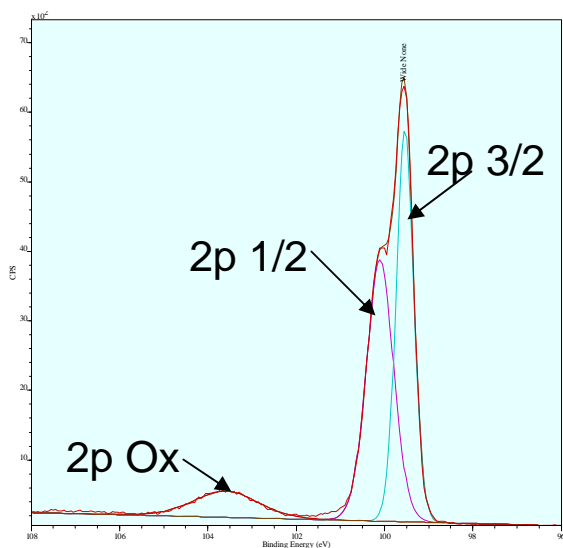
Name	Pos.	FWHM	Area	At%
O 1s	533	3.06708	8831.5	6.38
C 1s	285	2.80737	26758.3	56.60
N 1s	400	3.19643	1254.1	1.47
F 1s	687	2.94095	412.9	0.20
Br 3p	184	3.80632	17167.9	7.22
Si 2p	100	2.48349	10863.7	28.13

MB Wide

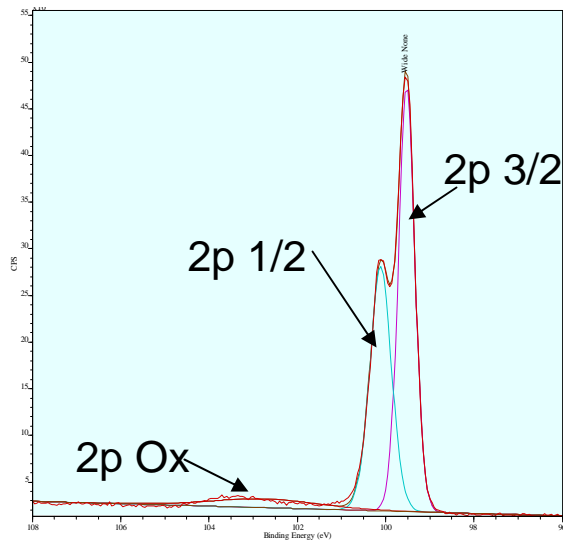


Name	Pos.	FWHM	Area	At%
O 1s	533	3.09062	18332.9	12.87
C 1s	285	3.31614	24542.7	50.48
N 1s	400	3.23162	1129.4	1.29
Si 2p	100	2.49079	14042.9	35.36

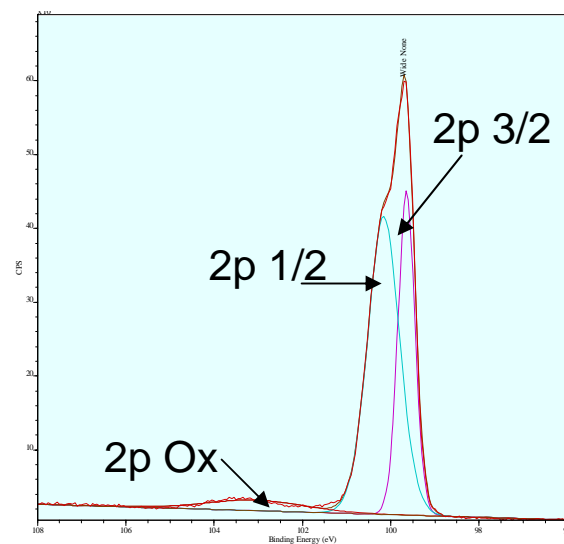
- Expanded view of Si 2p



Nitrobenzene



Bromobenzene



Methoxybenzene

2p Ox: sample oxidation (red)
2p 1/2: spin-orbit splitting (teal)
2p 3/2: spin-orbit splitting (purple)

- Sample Oxidation

NB	Position	% Conc.
Si 2p 1/2	101.1	45.29
Si 2p 3/2	99.5	43.75
Si 2p Ox	103.6	10.96

Surface Oxidation: 4.3%

BB	Position	% Conc.
Si 2p 1/2	100.1	39.89
Si 2p 3/2	99.5	53.01
Si 2p Ox	102.7	7.10

Surface Oxidation: 1.99%

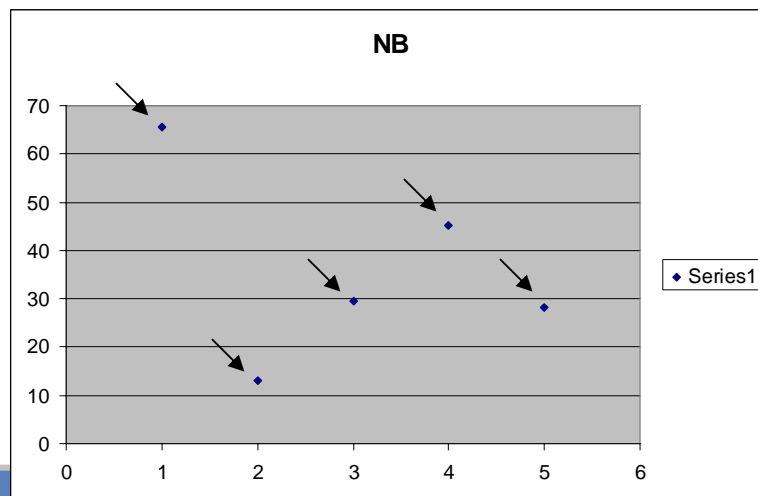
MB	Position	% Conc.
Si 2p 1/2	101.1	59.31
Si 2p 3/2	99.6	34.29
Si 2p Ox	103.0	6.40

Surface Oxidation: 2.26%

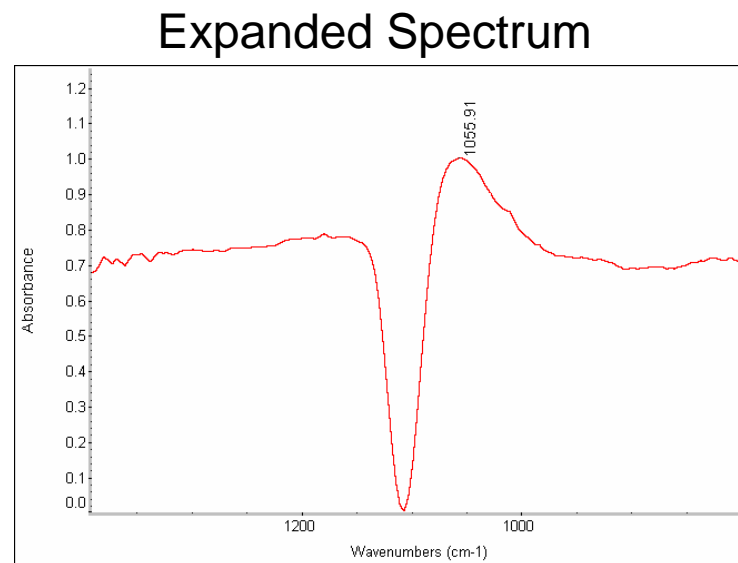
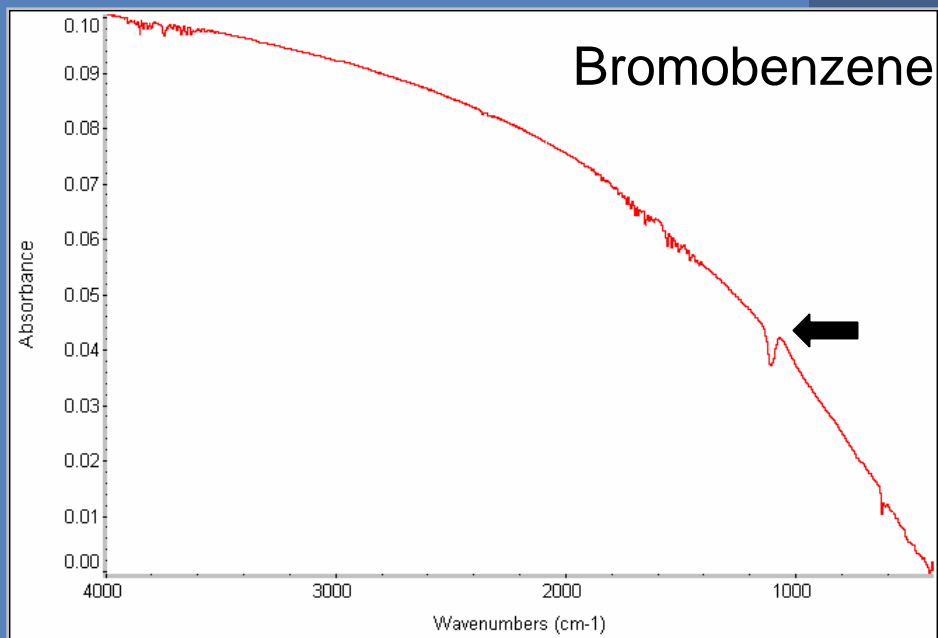
• Surface Characterization:
Depth Information

$$N_{elastic} = N_0 \left(1 - \exp\left\{ -\frac{d}{\lambda \cos \theta} \right\} \right)$$

NB	% Si 2p Ox	% Si 2p ₊₁	d	BB	% Si 2p Ox	% Si 2p ₊₁	d	MB	% Si 2p Ox	% Si 2p ₊₁	d
0	4.3	35.96	65.6		1.99	27.14	80.71		2.26	34.1	83.83
-30.06	4.88	35.38	13.05		2.02	27.11	17.1		1.88	34.49	19.16
-45	5.59	34.67	29.61		3.17	24.96	34.12		3.52	32.84	36.23
-59.94	7.27	32.99	45.27		4.59	24.54	48.85		4.01	32.35	62.49
-75.06	11.11	29.15	28.1086		4.7	24.43	48.03		4.86	31.5	54.46



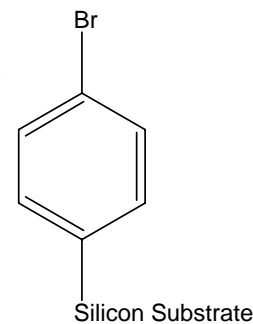
Graph is not linear:
Islands of oxidation on
sample surface

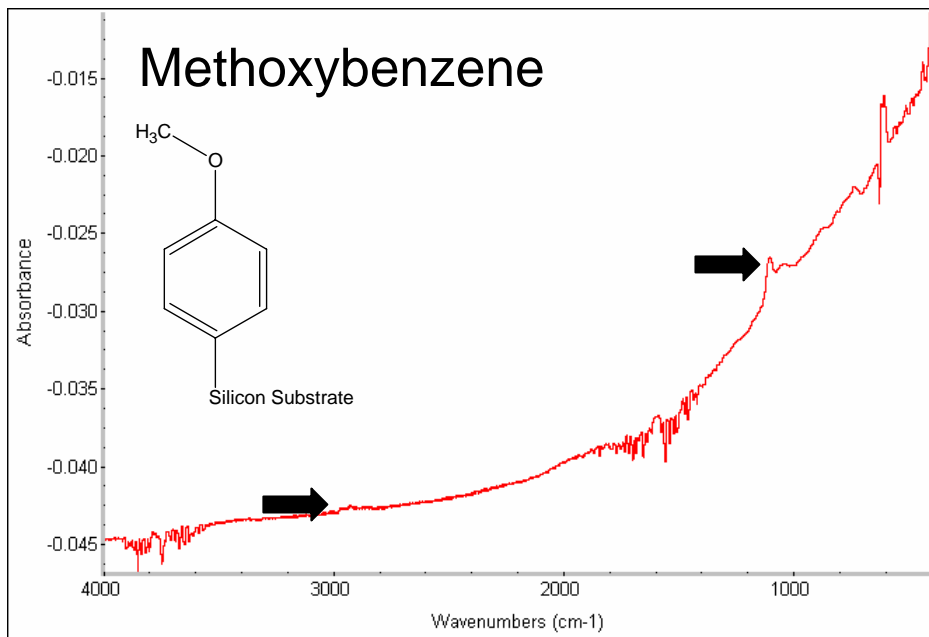


Bromobenzene

- Expected: C-Br peak $\sim 560-620\text{cm}^{-1}$
 - Aromatic $=\text{CH}_2$ $\sim 2950-3050\text{cm}^{-1}$
 - Aromatic C=C $\sim 1475-1600\text{cm}^{-1}$
- Peak present at 1055.91cm^{-1}
- Indicates oxidation of substrate
- No conclusive monolayer formation

**Molecular
Structure**

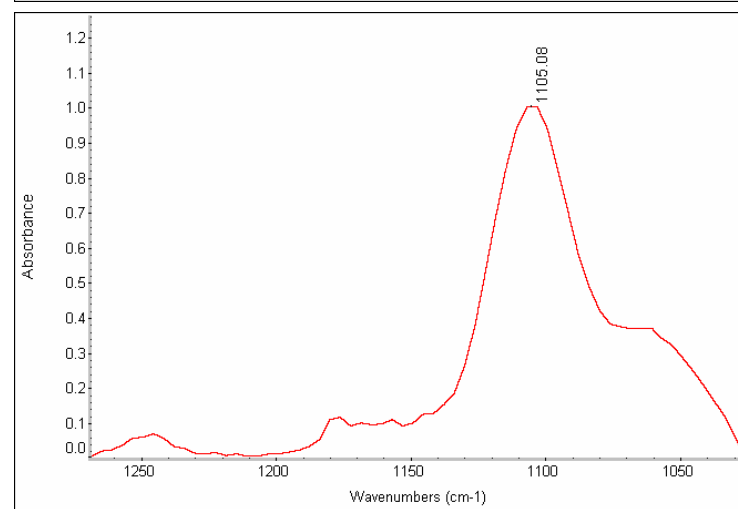
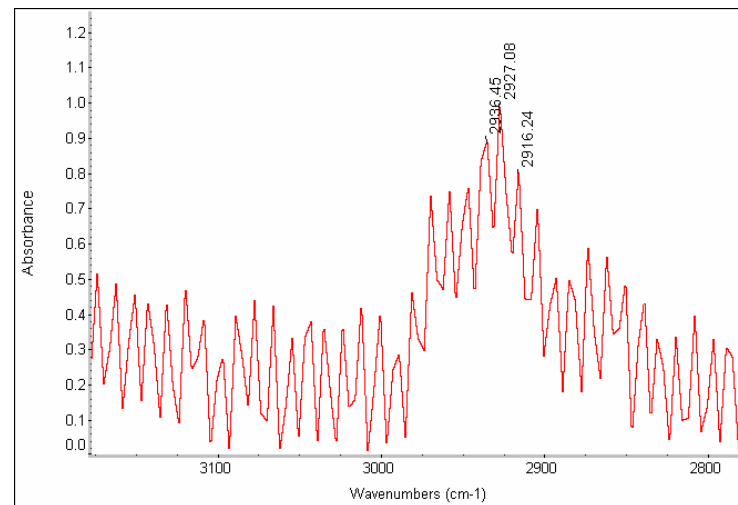


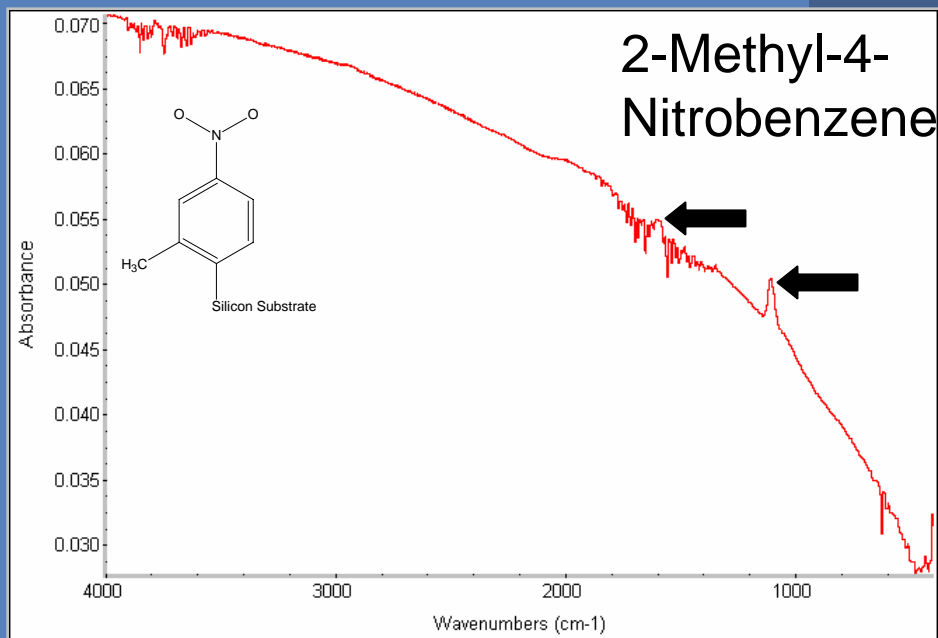


Methoxybenzene

- Expected: O-CH₃ ~2900-3000cm⁻¹
Aromatic C=C ~1475-1600cm⁻¹
- Peak present at 1105.08 cm⁻¹
- Indicates oxidation of substrate
- Peaks present at 2936.45, 2927.08, 2916.24cm⁻¹
- Indicates successful monolayer formation

Expanded Spectrum

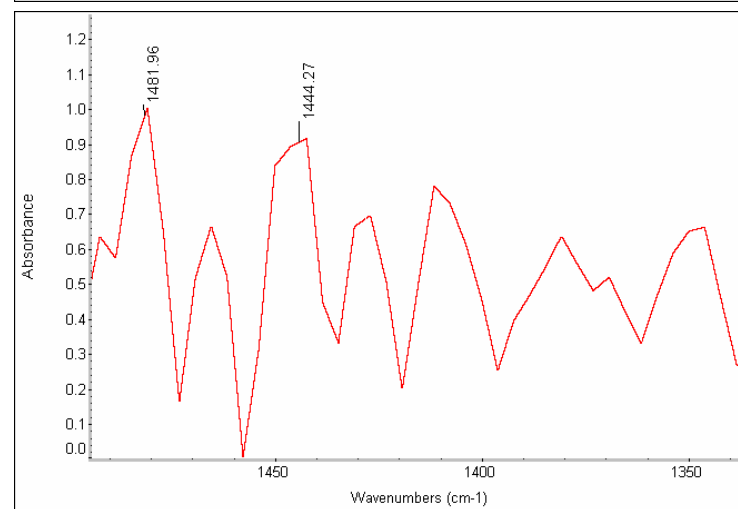
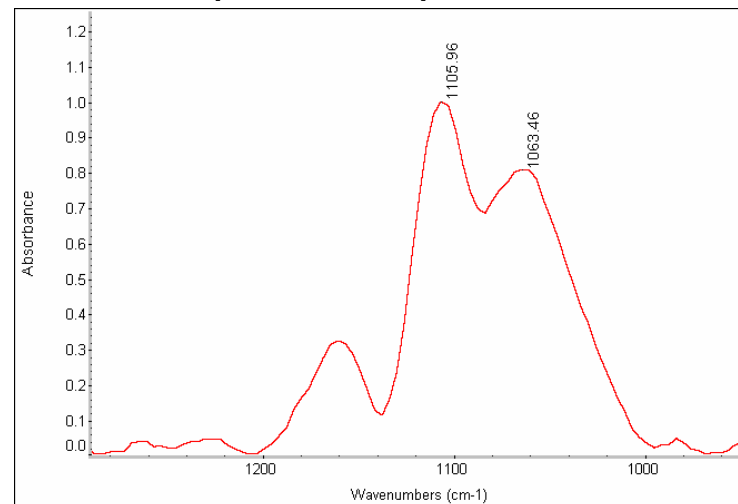


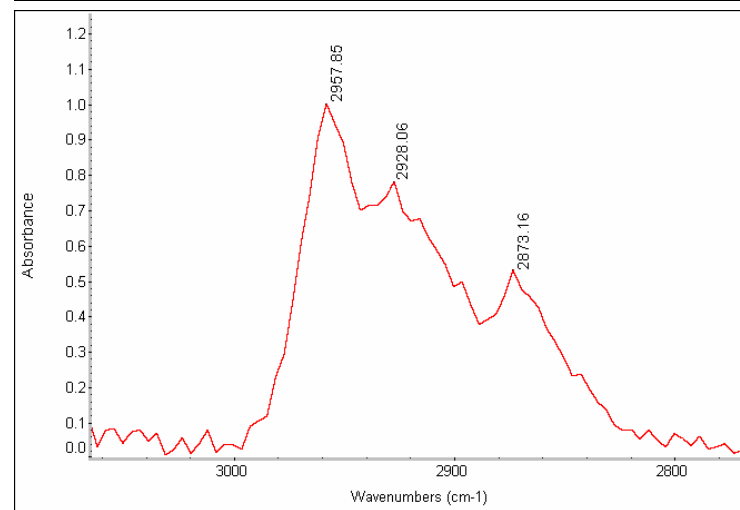
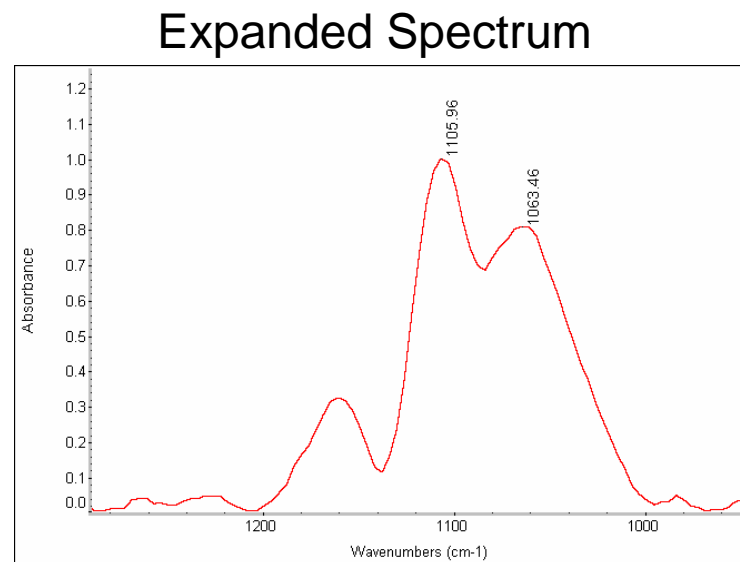
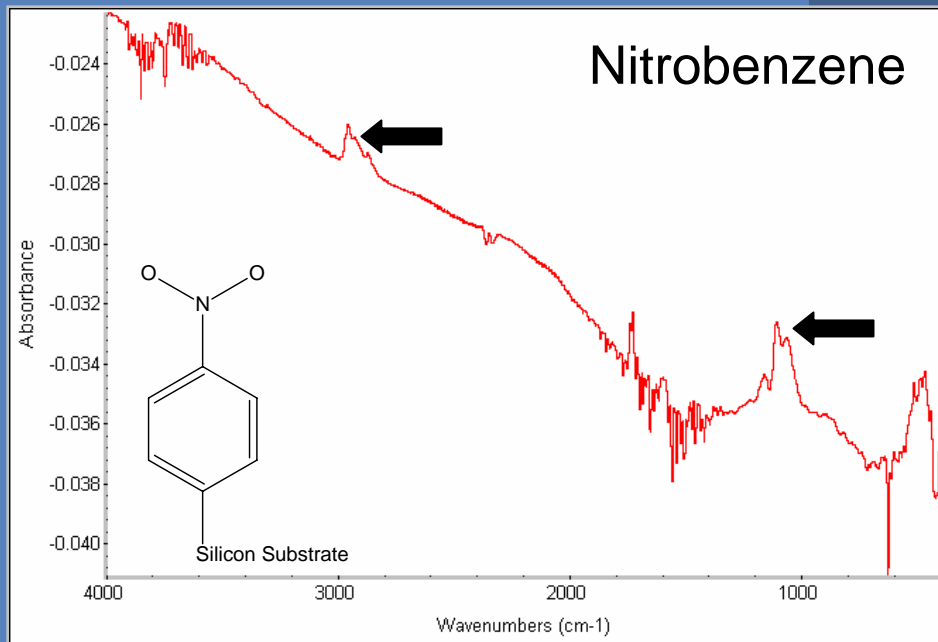


2-Methyl-4-Nitrobenzene

- Expected: N-O₂ peak ~1460cm⁻¹
Amine N-H₂ peak ~1350cm⁻¹
- Peak present at 1105.98cm⁻¹
- Indicates oxidation of substrate
- No other peaks present
- No conclusive monolayer formation

Expanded Spectrum





Nitrobenzene

- Expected: N-O₂ peak ~1460cm⁻¹
Amine N-H₂ peak ~1350cm⁻¹
- Peak present at 1105.96cm⁻¹ (Oxidation)
- Peaks present at 2957.85, 2908.06cm⁻¹
- Indicates semi-successful monolayer formation
- Broad peaks indicate unordered or multiple layers

- Solution immersion and self-assembly method were both effective in monolayer formation
- Self-assembly method with NH_4OH is more effective for monolayer formation upon GaAs (100) as shown by peak intensity
- Contacting molecule with Au resulted in a highly-ordered, low-penetrated compound when using self-assembly method

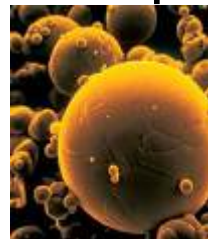
- FTIR of nitrobenzene and methoxybenzene indicate semi-successful monolayer formation on Si (111), although multiple layers may have been present on nitrobenzene
- FTIR of bromobenzene and 2-methyl-4-nitrobenzene indicate no indication of successful monolayer formation on Si (111)
- XPS results indicate successful monolayer formation of all the functional groups tested
- XPS indicate show ~2-4% oxidation upon substrates when using the electrochemical reduction method, often in islands

- Extension of two-dimensional capabilities into three dimensions

- Carbon nanotubes
- Nanoparticles
- Dendrimers
- Molecular wires



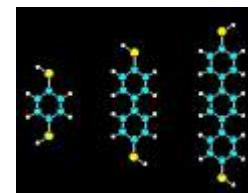
www.ewels.info



nanobot.blogspot.com



www.cdtltd.co.uk



www.physics.purdue.edu

- Molecular level control of integrated molecular systems will result in useful nanodevices
- Concern
 - Long-term stability and robustness of alkanethiol chemistry
 - Research possible systems with more robust bonds or use new alkyl chains
 - Functional device yield

A special thanks to...

- NASA
- INAC
- SURI 2006
- Purdue University
- Professor David Janes
- Patrick Carpenter and Adina Scott

